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PATENTS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: William D. Sawyer, et al.
Serial No.: 10/642,315
Filed: August 15, 2003
Title: Method for Microfabricating Structures Using Silicon-On-Insulator Material
Docket: CSLL-662CP (56247-235)

CERTIFICATE OF MAILING (37 C.F.R. § 1.8(a))

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail under 37 CFR 1.8(a) in an envelope addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below.

Date: 10/18/04


Weiguo Chen

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL LETTER

Applicant encloses herewith for filing in connection with the above-referenced patent application the following documents:

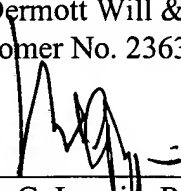
- 1) Information Disclosure Statement;
- 2) Information Disclosure Citation (PTO Form 1449);
- 3) Copies of the references cited; and
- 4) Acknowledgment Postcard.

No additional costs are believed to be due in connection with the filing of this disclosure. However, please charge any necessary fees to our Deposit Account No. 50-1133.

Respectfully submitted,

McDermott Will & Emery LLP
Customer No. 23630

Date: 10/16/04


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

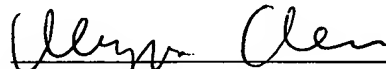
PATENT

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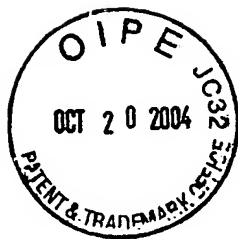
Sir:

INFORMATION DISCLOSURE STATEMENT

In accordance with 37 C.F.R. §1.56, §1.97 and §1.98, Applicants hereby submit an information disclosure statement with information cited on the attached PTO-1449 form. According to the United States Patent and Trademark Office OG Notices: 05 August 2003, since the above-identified patent application was filed after June 30, 2003, copies of cited U.S. patents and U.S. patent application publications are waived and not submitted with this Statement.

This Statement is being filed before the receipt of any Official Action from the Patent and Trademark Office.

This statement is not to be interpreted as a representation that the cited publications are material, that an exhaustive search has been conducted, or that no other relevant information exists. Nor shall the citation of any publication herein be construed *per se* as a representation that such publication is prior art. Moreover, the Applicant understands that the Examiner will make an independent evaluation of the cited publications.



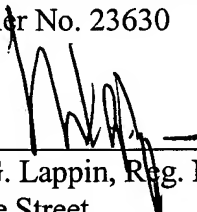
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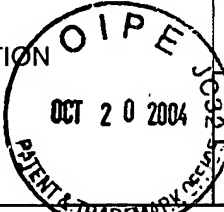
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Subst. Form PTO-1449		Docket Number (Optional) 56247-235 (CSLL-662CP)		Application Number 10/642,315			
INFORMATION DISCLOSURE CITATION IN AN APPLICATION <i>(Use several sheets if necessary)</i>							
		Applicant Sawyer, et al.					
		Filing Date 8/15/2003		Group Art Unit			
U. S. Patent Documents							
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		6,077,721	06-2000	Fukuda et al.			
		6,277,666	08-2001	Hays et al.			
		6,431,714	08-2002	Sawada et al.			
		6,423,563	07-2002	Fukads			
		4,079,508	03-1979	Nunn			
		6,252,294	06-2002	Hattori			
		6,171,881	01-2002	Fujii			
		5,488,012	01-1996	McCarthy			
		5,760,443	06-1998	McCarthy			
		3,922,705	11-1975	Yerman			
		6,105,427	08-2000	Stewart, et al.			
		6,458,615	10-2002	Fedder, et al.			
		5,501,893	03-1996	Laermer, et al.			
FOREIGN PATENT DOCUMENTS							
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES NO
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Copy of International Search Report PCT/US02/00015					
	C1	Moore DF, "Silicon-on insulator material for sensors and accelerometers" Silicon Fabricated Inertial instruments, 9/1-9/5 (December 1996)					
	C2	Syms RRA et al., "Surface tension powered self-assembly of 3D MOEMS devices using DRIE of bonded silicon-on-insulator wafers." IEEE Seminar on Demonstrated Micromachining Technologies for Industry, 1/1-1/6 (March 2000)					
	C3	Yamamoto T et al. "Capacitive accelerometer with high aspect ratio single crystalline silicon microstructure using SOI structure with polysilicon-based interconnect technique." Micro Electro Mechanical Systems, 515-519 (January 2000)					
	C4	Martin A. Schmidt, "Wafer-to-Wafer Bonding for Microstructure Formation", Proceedings of the IEEE, Vol. 86, No. 8, August 1998.					
EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy with next communication to applicant.							